

L Number	Hits	Search Text	DB	Time stamp
5	995363	test\$3	USPAT; US-PGPUB	2004/04/07 21:12
6	614886	monitor\$3	USPAT; US-PGPUB	2004/04/07 21:12
9	19565	test\$3 near (wafer\$1 or substrate\$1 or structure\$1)	USPAT; US-PGPUB	2004/04/07 21:15
10	4707	monitor\$3 near (wafer\$1 or substrate\$1 or structure\$1)	USPAT; US-PGPUB	2004/04/07 21:16
11	28439	CMP	USPAT; US-PGPUB	2004/04/07 21:16
12	24902	(chemical\$2 near mechanical\$2) adj polish\$3	USPAT; US-PGPUB	2004/04/07 21:16
13	3714	(chemical\$2 near mechanical\$2) adj planariz\$35	USPAT; US-PGPUB	2004/04/07 21:17
14	44950	trench\$2	USPAT; US-PGPUB	2004/04/07 21:17
21	1386	((test\$3 near (wafer\$1 or substrate\$1 or structure\$1)) or (monitor\$3 near (wafer\$1 or substrate\$1 or structure\$1))) and (CMP or ((chemical\$2 near mechanical\$2) adj polish\$3) or ((chemical\$2 near mechanical\$2) adj planariz\$35))	USPAT; US-PGPUB	2004/04/07 21:51
22	12669	SOI	USPAT; US-PGPUB	2004/04/07 21:51
23	6	silicon adj on adj insulat\$3	USPAT; US-PGPUB	2004/04/07 21:52
24	6740	silicon?on?insulat\$3	USPAT; US-PGPUB	2004/04/07 21:52
25	120	((test\$3 near (wafer\$1 or substrate\$1 or structure\$1)) or (monitor\$3 near (wafer\$1 or substrate\$1 or structure\$1))) and trench\$2 and (SOI or (silicon adj on adj insulat\$3) or silicon?on?insulat\$3)	USPAT; US-PGPUB	2004/04/07 21:53
26	1333	((test\$3 near (wafer\$1 or substrate\$1 or structure\$1)) or (monitor\$3 near (wafer\$1 or substrate\$1 or structure\$1))) and trench\$2	USPAT; US-PGPUB	2004/04/07 21:53